

CLAIM AMENDMENTS

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (currently amended) An electroosmotic pump comprising:
 - a. at least one porous structure for pumping fluid therethrough and having an average pore size, the porous structure having a first side and a second side and having a first continuous layer of electrically conductive porous material having an appropriate a first thickness along an axis parallel to an overall direction of fluid flow disposed on the first side, wherein the first thickness is less than the average pore size and a second continuous layer of electrically conductive porous material having a second thickness along the axis parallel to the overall direction of fluid flow disposed on the second side, wherein the second thickness is less than the average pore size, wherein at least a portion of the porous structure is configured to channel flow therethrough; and
 - b. means for providing electrical voltage to the first layer and the second layer to produce an electrical field therebetween, wherein the means for providing is coupled to the first layer and the second layer.
2. (original) The electroosmotic pump according to claim 1 further comprising means for generating power sufficient to pump fluid through the porous structure at a desired rate, wherein the means for generating is coupled to the means for providing.
3. (original) The electroosmotic pump according to claim 1 wherein the porous structure includes a plurality of fluid channels extending between the first side and the second side.
4. (original) The electroosmotic pump according to claim 1 wherein the first side and the second side are roughened.
5. (original) The electroosmotic pump according to claim 3 wherein the plurality of fluid channels are in a straight parallel configuration.

- 1 6. (original) The electroosmotic pump according to claim 3 wherein the plurality of fluid
2 channels are in a non-parallel configuration.
- 1 7. (original) The electroosmotic pump according to claim 3 wherein at least two of the
2 plurality of fluid channels are cross connected.
- 1 8. (original) The electroosmotic pump according to claim 1 wherein the electrically
2 conductive porous material is disposed as a thin film electrode.
- 1 9. (original) The electroosmotic pump according to claim 1 wherein the electrically
2 conductive porous material is disposed as a screen mesh having an appropriate
3 electrically conductivity.
- 1 10. (original) The electroosmotic pump according to claim 1 wherein the electrically
2 conductive porous material includes a plurality of conductive beads having a first
3 diameter in contact with one another to pass electrical current.
- 1 11. (original) The electroosmotic pump according to claim 10 wherein at least one of the
2 plurality of beads has a second diameter larger than the first diameter.
- 1 12. (original) The electroosmotic pump according to claim 1 wherein a predetermined portion
2 of the continuous layer of electrically conductive porous material has a third thickness.
- 1 13. (original) The electroosmotic pump according to claim 12 wherein the predetermined
2 portion of the continuous layer is disposed on the surface of the porous structure in one or
3 more desired patterns.
- 1 14. (original) The electroosmotic pump according to claim 13 wherein at least one of the
2 desired patterns further comprises a circular shape.
- 1 15. (original) The electroosmotic pump according to claim 13 wherein at least one of the
2 desired patterns further comprises a cross-hatched shape.

- 1 16. (original) The electroosmotic pump according to claim 13 wherein at least one of the
2 desired patterns further comprises a plurality of parallel lines.
- 1 17. (original) The electroosmotic pump according to claim 1 wherein at least a portion of an
2 outer region of the porous structure is made of fused non-porous glass.
- 1 18. (original) The electroosmotic pump according to claim 1 wherein the first thickness is
2 within the range between and including 200 Angstroms and 10,000 Angstroms.
- 1 19. (original) The electroosmotic pump according to claim 1 wherein the second thickness is
2 within the range between and including 200 Angstroms and 10,000 Angstroms.
- 1 20. (original) The electroosmotic pump according to claim 1 wherein the electrically
2 conductive porous material is Platinum.
- 1 21. (original) The electroosmotic pump according to claim 1 wherein the electrically
2 conductive porous material is Palladium.
- 1 22. (original) The electroosmotic pump according to claim 1 wherein the electrically
2 conductive porous material is Tungsten.
- 1 23. (original) The electroosmotic pump according to claim 1 wherein the electrically
2 conductive porous material is Copper.
- 1 24. (original) The electroosmotic pump according to claim 1 wherein the electrically
2 conductive porous material is Nickel.
- 1 25. (original) The electroosmotic pump according to claim 1 further comprising an adhesion
2 material disposed in between the electrically conductive porous material and the porous
3 structure.
- 1 26. (original) The electroosmotic pump according to claim 1 wherein the first layer and the
2 second layer is made of the same electrically conductive porous material.

- 1 27. (original) The electroosmotic pump according to claim 1 wherein the first layer and the
2 second layer is made of different electrically conductive porous materials.
- 1 28. (currently amended) An electroosmotic porous structure adapted to pump fluid
2 therethrough, the porous structure comprising a first side and a second side, the porous
3 structure having a plurality of fluid channels therethrough, the first side having a first
4 continuous layer of ~~electrically conductive porous material~~ thin film electrode deposited
5 thereon and the second side having a second continuous layer of ~~electrically conductive~~
6 ~~porous material~~ thin film electrode deposited thereon, the first layer and the second layer
7 coupled to a power source, wherein the power source supplies a voltage differential
8 between the first layer and the second layer to drive fluid through the porous structure at a
9 desired flow rate.
- 1 29. (original) The electroosmotic porous structure according to claim 28 wherein the plurality
2 of fluid channels extend from the first side to the second side in a straight parallel
3 configuration.
- 1 30. (original) The electroosmotic porous structure according to claim 28 wherein the plurality
2 of fluid channels extend from the first side to the second side in a non-parallel
3 configuration.
- 1 31. (original) The electroosmotic porous structure according to claim 28 wherein at least two
2 of the plurality of fluid channels are cross connected.
- 1 32. (canceled)
- 1 33. (original) The electroosmotic porous structure according to claim 28 wherein the first
2 layer of electrically conductive porous material is a screen mesh.

- 1 34. (original) The electroosmotic porous structure according to claim 28 wherein the
2 electrically conductive porous material further comprises a plurality of conductive beads
3 having a first diameter in contact with one another to pass electrical current.
- 1 35. (original) The electroosmotic porous structure according to claim 34 wherein at least one
2 of the plurality of beads has a second diameter larger than the first diameter.
- 1 36. (original) The electroosmotic porous structure according to claim 28 wherein a
2 predetermined portion of the continuous layer of electrically conductive porous material
has a third thickness.
- 1 37. (original) The electroosmotic porous structure according to claim 36 wherein the
2 predetermined portion of the continuous layer is disposed on the surface of the porous
3 structure in one or more desired patterns.
- 1 38. (original) The electroosmotic porous structure according to claim 28 wherein at least a
2 portion of an outer region of the porous structure is made of fused non-porous glass.
- 1 39. (original) The electroosmotic porous structure according to claim 28 wherein the
2 continuous layer has a thickness within the range between and including 200 Angstroms
3 and 10,000 Angstroms.
- 1 40. (original) The electroosmotic porous structure according to claim 28 wherein the
2 electrically conductive porous material is Platinum.
- 1 41. (original) The electroosmotic porous structure according to claim 28 wherein the
2 electrically conductive porous material is Palladium.
- 1 42. (original) The electroosmotic porous structure according to claim 28 wherein the
2 electrically conductive porous material is Tungsten.
- 1 43. (original) The electroosmotic porous structure according to claim 28 wherein the
2 electrically conductive porous material is Nickel.

- 1 44. (original) The electroosmotic porous structure according to claim 28 wherein the
2 electrically conductive porous material is Copper.
- 1 45. (original) The electroosmotic porous structure according to claim 28 further comprising
2 an adhesion material disposed in between the electrically conductive porous material and
3 the porous structure.
- 1 46. (withdrawn) A method of manufacturing an electroosmotic pump comprising the steps of:
2 a. forming at least one porous structure having a first side and a second side and a
3 plurality of fluid channels therethrough;
4 b. depositing a first continuous layer of electrically conductive porous material of
5 appropriate first thickness to the first side adapted to pass fluid through at least a
6 portion of the portion of the first layer; and
7 c. depositing a second continuous layer of electrically conductive porous material of
8 appropriate second thickness to the second side adapted to pass fluid through at
9 least a portion of the second layer.
- 1 47. (withdrawn) The method according to claim 46 wherein the plurality of fluid channels
2 extend from the first side to the second side in a straight parallel configuration.
- 1 48. (withdrawn) The method according to claim 46 wherein the plurality of fluid channels
2 extend from the first side to the second side in a non-parallel configuration.
- 1 49. (withdrawn) The method according to claim 46 further comprising the steps of:
2 a. coupling a power source to the first continuous layer and the second continuous
3 layer; and
4 b. applying an appropriate amount of voltage to generate a substantially uniform
5 electric field across the at least one porous structure.
- 1 50. (withdrawn) The method according to claim 49 wherein the power source is coupled to
2 the first and second continuous layers via a pair of wires.

- 1 51. (withdrawn) The method according to claim 46 wherein the layer of electrically
2 conductive porous material is a thin film.
- 1 52. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is a screen mesh.
- 1 53. (withdrawn) The method according to claim 52 further comprising the step of
2 mechanically clamping the screen mesh to the porous structure.
- 1 54. (withdrawn) The method according to claim 46 wherein the layer of electrically
2 conductive porous material includes a plurality of conductive beads in contact with one
3 another.
- 1 55. (withdrawn) The method according to claim 46 wherein a predetermined portion of the
2 layer of electrically conductive porous material has a third thickness.
- 1 56. (withdrawn) The method according to claim 46 wherein at least a portion of an outer
2 region of the porous structure is made of fused non-porous glass.
- 1 57. (withdrawn) The method according to claim 46 wherein the first thickness is within the
2 range between and including 200 Angstroms and 10,000 Angstroms.
- 1 58. (withdrawn) The method according to claim 46 wherein the second thickness is within
2 the range between and including 200 Angstroms and 10,000 Angstroms.
- 1 59. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is Platinum.
- 1 60. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is Copper.
- 1 61. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is Palladium.

- 1 62. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is Tungsten.
- 1 63. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is Nickel.
- 1 64. (withdrawn) The method according to claim 46 further comprising the step of depositing
2 an adhesion material to a surface of the electrically conductive porous material.
- 1 65. (withdrawn) The method according to claim 46 further comprising an adhesion material
2 disposed in between the electrically conductive porous material and the second side of the
3 porous structure.
- 1 66. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is applied by an evaporation process.
- 1 67. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is applied by a vapor deposition process.
- 1 68. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is applied by a screen printing process.
- 1 69. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is applied by a spraying process.
- 1 70. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is applied by a sputtering process.
- 1 71. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is applied by a dispensing process.
- 1 72. (withdrawn) The method according to claim 46 wherein the electrically conductive

1 porous material is applied by a dipping process.

1 73. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is applied by a spinning process.

1 74. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is applied as a conductive ink.

1 75. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is applied by a patterning process.

1 76. (withdrawn) The method according to claim 46 wherein the electrically conductive
2 porous material is applied by a shadow masking process.

1 77. (new) An electroosmotic pump comprising:

2 a. at least one porous structure for pumping fluid therethrough, the porous structure
3 having a first side and a second side and having a first continuous layer of
4 electrically conductive porous material having an appropriate first thickness
5 disposed on the first side and a second continuous layer of electrically conductive
6 porous material having a second thickness disposed on the second side wherein at
7 least a portion of the porous structure is configured to channel flow therethrough,
8 and wherein the first side and the second side are roughened; and

9 b. means for providing electrical voltage to the first layer and the second layer to
10 produce an electrical field therebetween, wherein the means for providing is
11 coupled to the first layer and the second layer.

1 78. (new) An electroosmotic pump comprising:

2 a. at least one porous structure for pumping fluid therethrough, the porous structure
3 having a first side and a second side and having a first continuous layer of
4 electrically conductive porous material having an appropriate first thickness
5 disposed on the first side and a second continuous layer of electrically conductive
6 porous material having a second thickness disposed on the second side wherein at
7 least a portion of the porous structure is configured to channel flow therethrough,

- 1 and wherein the porous structure includes a plurality of fluid channels extending
2 in a non-parallel configuration between the first side and the second side; and
3 b. means for providing electrical voltage to the first layer and the second layer to
4 produce an electrical field therebetween, wherein the means for providing is
5 coupled to the first layer and the second layer.

1 79. (new) An electroosmotic pump comprising:

- 2 a. at least one porous structure for pumping fluid therethrough, the porous structure
3 having a first side and a second side and having a first continuous layer of
4 electrically conductive porous material having an appropriate first thickness
5 disposed on the first side and a second continuous layer of electrically conductive
6 porous material having a second thickness disposed on the second side wherein at
7 least a portion of the porous structure is configured to channel flow therethrough,
8 and wherein the porous structure includes a plurality of fluid channels extending
9 between the first side and the second side, wherein at least two of the plurality of
10 fluid channels are cross connected; and
11 b. means for providing electrical voltage to the first layer and the second layer to
12 produce an electrical field therebetween, wherein the means for providing is
13 coupled to the first layer and the second layer.

15 80. (new) An electroosmotic pump, comprising:

- 16 a. a porous structure forming therein a plurality of passages coupling a first set of
17 apertures on a first surface to a second set of apertures on a second surface,
18 wherein at least one of the first set of apertures and the second set of apertures
19 forms a two-dimensional pattern on its surface;
20 b. a first layer of electrically conductive porous material deposited on the first
21 surface and configured so that fluid can pass through the first layer, through the
22 first set of apertures and into the plurality of passages;
23 c. a second layer of electrically conductive porous material deposited on the second
24 surface and configured so that fluid can pass from the plurality of passages
25 through the second set of apertures and through the second layer; and
26 d. means for providing electrical voltage to the first layer and the second layer to
27 produce an electrical field therebetween, wherein the means for providing is

1 coupled to the first layer and the second layer.
2

- 3 81. (new) An electroosmotic porous structure adapted to pump fluid therethrough, the porous
4 structure comprising a first side with a first set of apertures therein and a second side with
5 a second set of apertures therein, the porous structure having a plurality of fluid channels
6 therethrough coupling the first set of apertures to the second set of apertures, the first side
7 having a first continuous layer of electrically conductive porous material deposited
8 thereon so that each of the first set of apertures is surrounded by a continuous structure of
9 electrically conductive porous material and the second side having a second continuous
10 layer of electrically conductive porous material deposited thereon so that each of the
11 second set of apertures is surrounded by a continuous structure of electrically conductive
12 porous material, the first layer and the second layer coupled to a power source, wherein
13 the power source supplies a voltage differential between the first layer and the second
14 layer to drive fluid through the porous structure at a desired flow rate.